

# A High-Sensitivity Near-Infrared Phototransistor Based on Organic Bulk Heterojunction

Haihua Xu,<sup>a</sup> Jun Li,<sup>b</sup> Billy H. K. Leung,<sup>c</sup> Carmen C. Y. Poon,<sup>c</sup> Beng S. Ong,<sup>d</sup> Yuanting Zhang,<sup>a</sup> and Ni Zhao<sup>\*a</sup>

*\*Department of Electronic Engineering, The Chinese University of Hong Kong, New Territories, Hong Kong, E-mail: nzhao@ee.cuhk.edu.hk*

## Support Information

### 1. Experimental Section

#### 1.1 Materials:

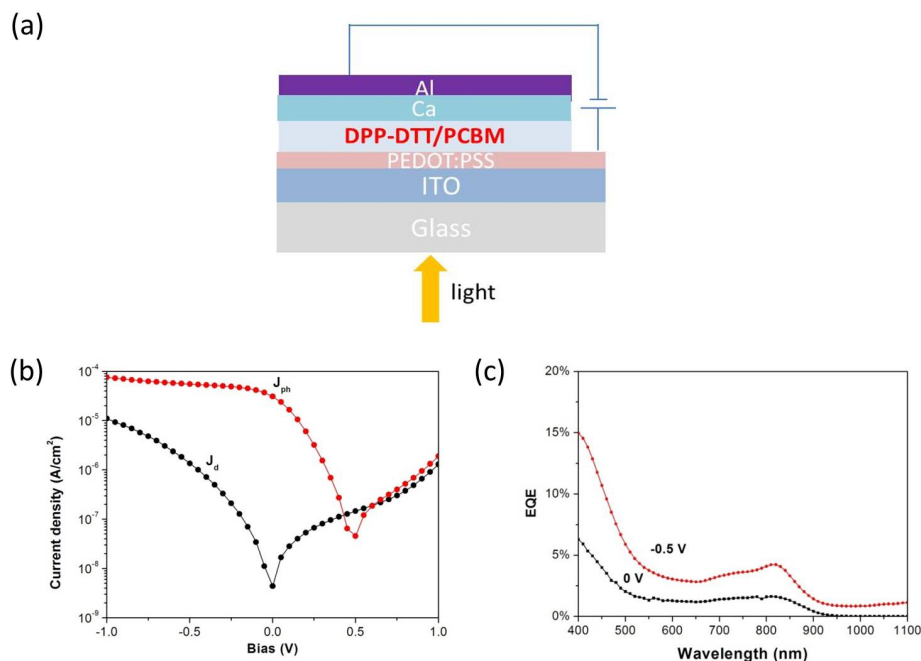
The DPP-DTT polymer was synthesized as reported Ref. 23. The molecular weight of DPP-DTT was determined by gel-permeation chromatography against polystyrene standards and the average molecular weight ( $M_n$ ) was 106, 000. 1-octanethiol, octyltrichlorosilane (OTS-8) and PCBM were purchased from Sigma-Aldrich Co. LLC.

#### 1.2 Device Fabrication:

The substrate is a heavily n-doped silicon wafer (used as the gate electrode) deposited with a 300 nm thickness SiO<sub>2</sub> film, which is used as a dielectric layer (capacitance: 10.5 nFcm<sup>2</sup>). The substrate was firstly cleaned ultrasonically in acetone and isopropyl alcohol (IPA) for 10 minutes, respectively, then immersed in solution of H<sub>2</sub>SO<sub>4</sub>/H<sub>2</sub>O<sub>2</sub> (1:1) for 5 minutes at room temperature. Gold source-drain electrodes with a thickness of 30 nm were defined by photolithography to get a channel length of L=10 μm and channel width of W=15 mm on the substrate. The substrate with gold electrodes was firstly immersed in 0.1 M solution of OTS-8 in toluene at 60 °C for 30 min, then immediately immersed in 10 mM solution of 1-octanethiol in IPA for 2 minutes at room temperature. A photosensitive thin film was then deposited by spin-coating the solution of DPP-DTT: PCBM (mass ratio 1:1) blend (concentration: 10 mg/mL) and annealed at 135 °C for 30 minutes in a nitrogen atmosphere.

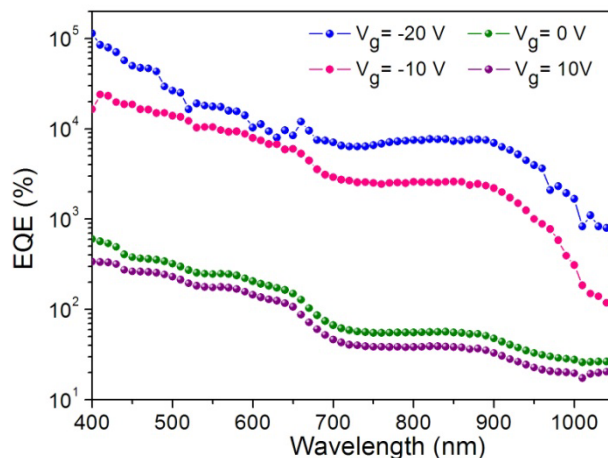
### 2. Results of the photodiode based on DPP-DTT/PCBM blends

A photodiode (Fig. S1a) based on DPP-DTT/PCBM blend is prepared for a comparative study. The film processing and measurement conditions for the photodiode were kept the same as the phototransistor. The J-V curves and the EQE spectra of the photodiode are shown below.



**Fig. S1.** (a) The schematic of photodiode based on DPP-DDT: PCBM (1:1) bulk heterojunction; (b) current-density versus voltage ( $J$ - $V$ ) of the photodiode measured in the dark ( $J_d$ ) and light conditions ( $J_{ph}$ ) ( $\lambda=808$  nm,  $P=3$  mW/cm<sup>2</sup>); (c) External quantum efficiency (EQE) at different bias voltages.

### 3. External quantum efficiency (EQE) of the phototransistor under different gate bias.



**Fig. S2** External quantum efficiency (EQE) versus gate voltage ( $V_d=-5$  V), the power intensity of the light source is 5  $\mu$ W cm<sup>-2</sup>.

### 4. Calculation of detectivity

The detectivity  $D^*$  of the photodetector is given by the following equation:

$$D^* = (A \cdot \Delta f)^{1/2} \cdot R \cdot i_n^{-1}$$

where  $A$  is the active area of the photodetector,  $\Delta f$  is the electrical bandwidth,  $R$  is the responsivity of the photodetector,  $i_n$  is the noise current which is determined by three

components: <sup>1,2</sup> shot noise, Johnson noise, and thermal fluctuation noise. In general, the noise current is dominated by the shot noise originated from dark current, thus, the  $D^*$  can be approximated as: <sup>3</sup>

$$D^* = R \cdot (2 \cdot q \cdot J_d)^{-1/2}$$

where  $q$  is the value of elementary charge ( $1.6 \times 10^{-19}$  Coulomb),  $J_d$  is the dark current.

- 1 A. R. Jha, *Infrared Technology Applications to Electrooptics, Photonic Devices, and Sensors*, Wiley, New York **2000**, pp. 245–438
- 2 P. Bhattacharya, *Semiconductor Optoelectronics Device*, Prentice-Hall, Upper Saddle River, NJ **1997**, pp. 345–367.
- 3 X. Gong, M. Tong, Y. Xia, W. Cai, J. S. Moon, Y. Cao, G. Yu, C-L. Shieh, B. Nilsson, A. J. Heeger, *Science* **2009**, 325, 1665.